Grzegorz Lupina

List of Publications by Year in descending order

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		471509	501196
33	1,515	17	28
papers	citations	h-index	g-index
33	33	33	2500
all docs	docs citations	times ranked	citing authors

#	Article	IF	CITATIONS
1	Contact resistance and mobility in back-gate graphene transistors. Nano Express, 2020, 1, 010001.	2.4	55
2	Contacting graphene in a 200†mm wafer silicon technology environment. Solid-State Electronics, 2018, 144, 17-21.	1.4	2
3	Hybrid graphene/silicon Schottky photodiode with intrinsic gating effect. 2D Materials, 2017, 4, 025075.	4.4	127
4	Tunable Schottky barrier and high responsivity in graphene/Si-nanotip optoelectronic device. 2D Materials, 2017, 4, 015024.	4.4	122
5	(Invited) Large Scale Graphene Integration for Silicon Technologies. ECS Transactions, 2017, 79, 3-10.	0.5	Ο
6	Perfluorodecyltrichlorosilane-based seed-layer for improved chemical vapour deposition of ultrathin hafnium dioxide films on graphene. Scientific Reports, 2016, 6, 29223.	3.3	12
7	Observation of field emission from GeSn nanoparticles epitaxially grown on silicon nanopillar arrays. Nanotechnology, 2016, 27, 485707.	2.6	51
8	Graphene growth on Ge(100)/Si(100) substrates by CVD method. Scientific Reports, 2016, 6, 21773.	3.3	83
9	Selective Epitaxy of InP on Si and Rectification in Graphene/InP/Si Hybrid Structure. ACS Applied Materials & Interfaces, 2016, 8, 26948-26955.	8.0	23
10	Photodetection in Hybrid Single-Layer Graphene/Fully Coherent Germanium Island Nanostructures Selectively Grown on Silicon Nanotip Patterns. ACS Applied Materials & Interfaces, 2016, 8, 2017-2026.	8.0	32
11	Graphene for Silicon Microelectronics: Ab Initio Modeling of Graphene Nucleation and Growth. Nanoscience and Technology, 2016, , 181-203.	1.5	Ο
12	Graphene field effect transistors with niobium contacts and asymmetric transfer characteristics. Nanotechnology, 2015, 26, 475202.	2.6	78
13	Direct growth of HfO2 on graphene by CVD. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, .	1.2	4
14	Atomic layer deposition of Al2O3on NF3-pre-treated graphene. , 2015, , .		2
15	Residual Metallic Contamination of Transferred Chemical Vapor Deposited Graphene. ACS Nano, 2015, 9, 4776-4785.	14.6	250
16	Graphene grown on Ge(0 0 1) from atomic source. Carbon, 2014, 75, 104-112.	10.3	54
17	Molecular beam growth of micrometer-size graphene on mica. Carbon, 2013, 52, 40-48.	10.3	36
18	Nucleation and growth of HfO2 layers on graphene by chemical vapor deposition. Applied Physics Letters, 2013, 103, .	3.3	16

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#	Article	IF	CITATIONS
19	A Graphene-Based Hot Electron Transistor. Nano Letters, 2013, 13, 1435-1439.	9.1	215
20	A manufacturable process integration approach for graphene devices. Solid-State Electronics, 2013, 84, 185-190.	1.4	24
21	Deposition of thin silicon layers on transferred large area graphene. Applied Physics Letters, 2013, 103, .	3.3	13
22	Graphene base hot electron transistors with high on/off current ratios. , 2013, , .		0
23	Vertical Graphene Base Transistor. IEEE Electron Device Letters, 2012, 33, 691-693.	3.9	141
24	Characterization of group II hafnates and zirconates for metal–insulator–metal capacitors. Physica Status Solidi (B): Basic Research, 2011, 248, 323-326.	1.5	16
25	Direct graphene growth on insulator. Physica Status Solidi (B): Basic Research, 2011, 248, 2619-2622.	1.5	59
26	Charge transfer and partial pinning at the contacts as the origin of a double dip in the transfer characteristics of graphene-based field-effect transistors. Nanotechnology, 2011, 22, 275702.	2.6	63
27	Improving the dielectric constant of Al2O3 by cerium substitution for high-k MIM applications. Surface Science, 2010, 604, 276-282.	1.9	20
28	Dielectric Properties of Thin Hf- and Zr-based Alkaline Earth Perovskite Layers. ECS Transactions, 2009, 25, 147-151.	0.5	2
29	Group-II Hafnate, Zirconate, and Tantalate High-k Dielectrics for MIM Applications: The Defect Issue. ECS Transactions, 2009, 25, 219-239.	0.5	3
30	Perovskite BaHfO ₃ Dielectric Layers for Dynamic Random Access Memory Storage Capacitor Applications. Advanced Engineering Materials, 2009, 11, 259-264.	3.5	6
31	Deposition of BaHfO ₃ Dielectric Layers for Microelectronic Applications by Pulsed Liquid Injection MOCVD. Chemical Vapor Deposition, 2009, 15, 167-170.	1.3	5
32	Morphology and Composition of Praseodymium Based High-k Materials and Their Relevance to Dielectric Properties of Thin-Films. ECS Transactions, 2007, 6, 773-805.	0.5	1
33	Charge Traps in High-k Dielectrics: Ab Initio Study of Defects in Pr-Based Materials. , 0, , 247-268.		0